

Tilted Fiber Bragg Gratings as new sensing device for in situ and real time monitoring of surface-initiated polymerization

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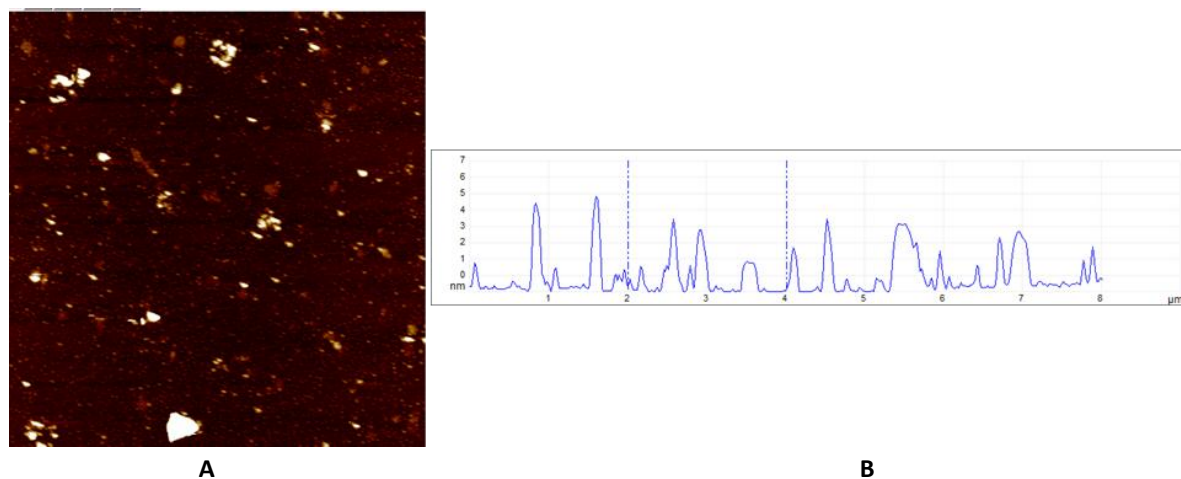


Figure S1 TM-AFM ($10 \times 10 \mu\text{m}^2$) of SAM prepared in dry CH_2Cl_2 a) Height images and b) section of silicon substrate covered with a SAM built in dry CH_2Cl_2 for 16 hours. Vertical scale bar is 3 nm.

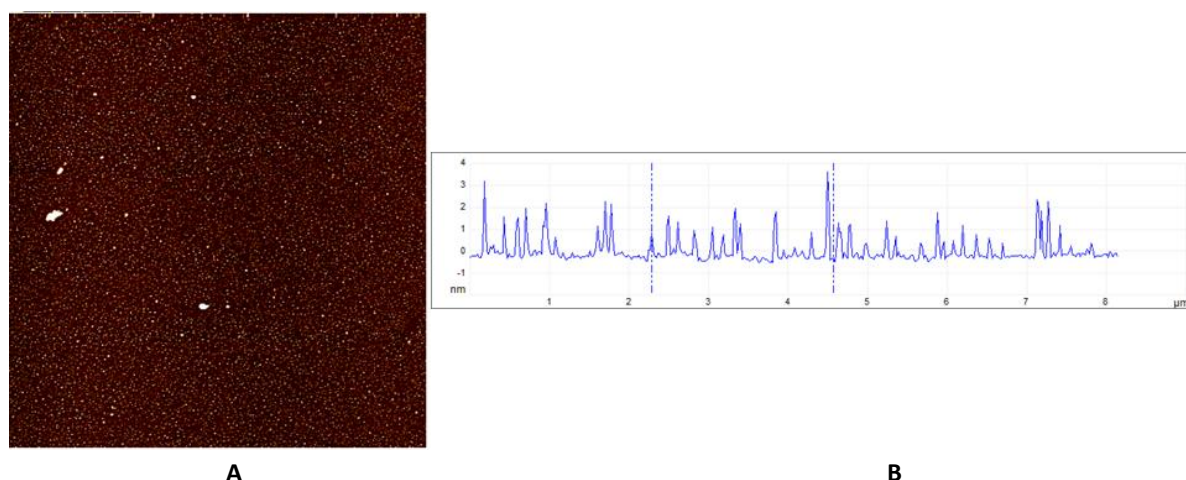


Figure S2 TM-AFM ($10 \times 10 \mu\text{m}^2$) of SAM prepared in dry toluene a) Height images and b) section of silicon substrate covered with a SAM built in dry toluene for 16 hours. Vertical scale bar is 4nm

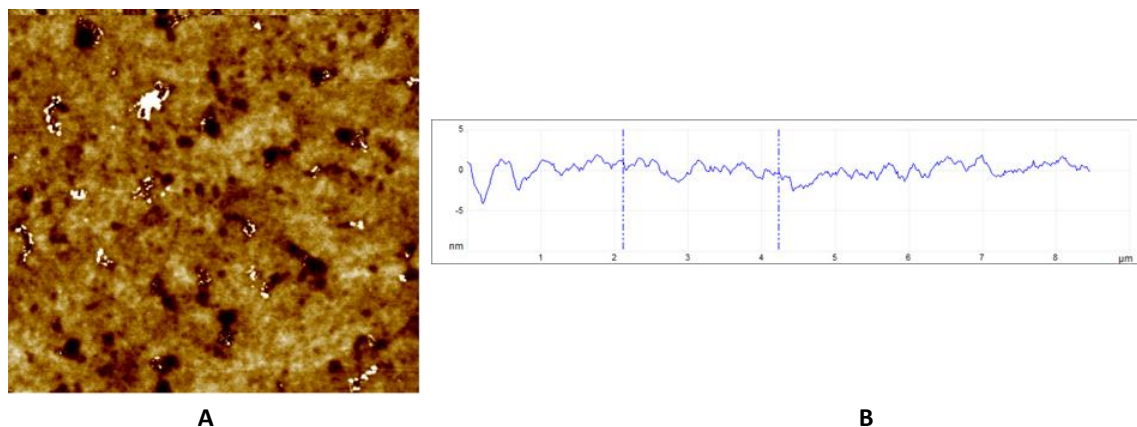


Figure S3 TM-AFM ($10 \times 10 \mu\text{m}^2$) of SAM prepared by vapor phase deposition a) height and b) section of silicon substrate covered with a SAM. Vertical scale bar is 4 nm

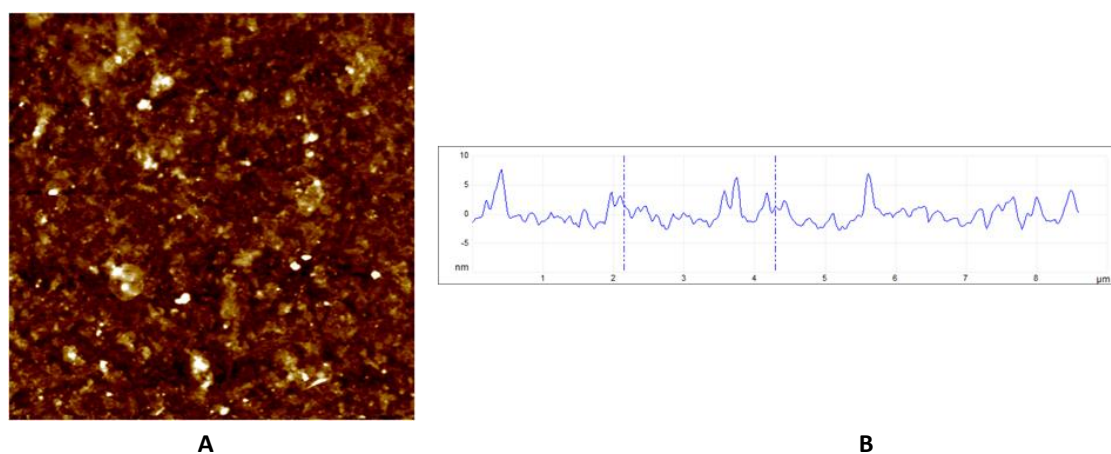


Figure S4 a) TM-AFM height image ($10 \times 10 \mu\text{m}^2$) of PDMAEMA brushes obtained by "grafting from" on silicon substrate. b) The height section is added. Vertical scale bar is 10nm.

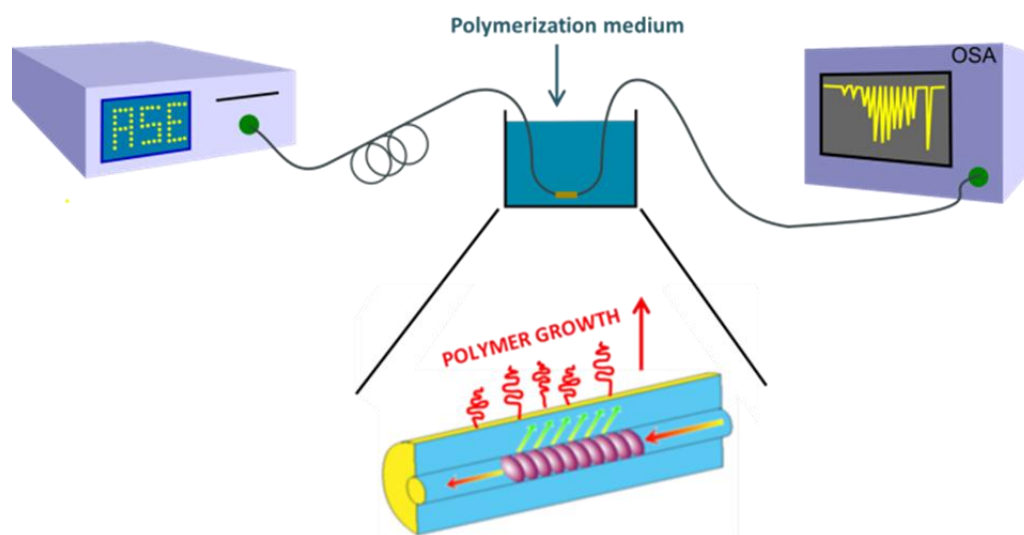


Figure S5 Scheme of an optical fiber used for these tests